

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

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Title of Invention

METHOD OF PLANARIZING SPIN-ON MATERIAL LAYER AND
MANUFACTURING PHOTORESIST LAYER

Application Number :

10 / 711,379

Confirmation Number:

First Named Applicant:

Jefferson Lu

Attorney Docket Number:

12474-US-PA

Art Unit:

Examiner:

Search string:

(6482716 or 6630397).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
PR	1	6482716	2002-11-19	Wohlfahrt et al.		438	427
PR	2	6630397	2003-10-07	Ding et al.		438	636

Signature

Examiner Name	Date
	4/26/05